Nano Machining Analysis

High Resolution SIMS + FIB

SIMS Analysis with Cs+ EDX-EDS Alternative

Nanofabrication Process Control with SIMS

Sectioning
Slice and View
Life Science
Semiconductor





Cs+ ion beam with nanometer resolution

10+ nA beam current

Full-featured FIB system

Highest resolution SIMS

Parallel readout of all masses

Obtain EDX-like spectra... without lamella prep!

Gather SIMS data 100X faster

Machine with higher precision

Endpoint using mass spectra

Nanofabrication process control using SIMS

More Analysis : Less Time

Existing Workflow: Thin Sample EDX

Load Sample in FIB/SEM

Locate ROI Prepare Lamella Transfer to TEM with ED

Locat

EDX Analysis

Only one shot: analysis limited to a single depth

Optimized Workflow - SIMS:ZERO

Load Sample in SIMS:ZERO

Locat ROI Prepare Cross Section

SIMS Analysis

SIMS Analysis on Deeper Plane SIMS Analysis on Deeper Plane

Introducing SIMS:ZERO

The Integrated Solution for

Nanomachining + High Resolution Elemental Analysis

Imagine obtaining EDX-like spectra without time-consuming trenching and lift-out. Imagine collecting SIMS data 100X faster and with ultimate spatial resolution. Imagine machining resolution better than any other FIB on the market.

Now imagine all of it in a single platform.

SIMS:ZERO **AVAII ABI F 2019**





About Us

zeroK NanoTech and the Luxembourg Institute of Standards and Technology are aiming to join together to deliver an entirely new class of analytic instrument. We are leveraging new Low Temperature Ion Source technology to achieve heretofore unprecedented levels of performance.



The Ultimate in Elemental Analysis

TEL: +1 240 702 0081 Email: info@zerok.com

401 Professional Drive. Ste 125 Gaithersburg, MD 20879

TaiwanAgent台灣總代理 AtomSemiconCo.,Ltd. General Manager/BobLin mobile:+886-986-968830 email:Bob.Lin@atom-semi.com B35 1A2, No.1, Lising 1st Rd., East Dist., HsinchuCity300, Taiwan (R.O.C.)



www.zerok.com



